

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In r Application of: Zongtao GE

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For: Phase Shift Fringe Analysis Method and Apparatus Using the Same

APPLICATION DATA SHEET(1) APPLICANT INFORMATIONSole Inventor

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(3) APPLICATION INFORMATIONTitle

Phase Shift Fringe Analysis Method and Apparatus Using the Same

Total # Draw Sheets

5

Suggested Figure forPublication

1

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Type of Application

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(4) REPRESENTATIVE INFORMATION

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(5) DOMESTIC PRIORITY INFORMATION

None

(6) FOREIGN PRIORITY INFORMATION

Application Number 2001-23200
Country Japan
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(7) ASSIGNEE INFORMATION

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